



Fabrication and application of 3D force sensors based on piezoelectric and piezoresistive effects

János Radó

MTA EK MFA MEMS laboratory

Fifth semester

Supervisor: Csikósné Papp Andrea Edit

Introduction

3 parts of my work

- Piezoresistive 3D force sensors***
- Piezoelectric ZnO nano-rods***
- Piezoelectric thin films (for 3D force sensor)***

Piezoresistive 3D force sensors

Applications

- Integration in a surgery robot's laparoscope***
- Integration in a vehicle tyre***

Piezoresistive 3D force sensors - Integration in a laparoscopic tool

3D force sensor chip

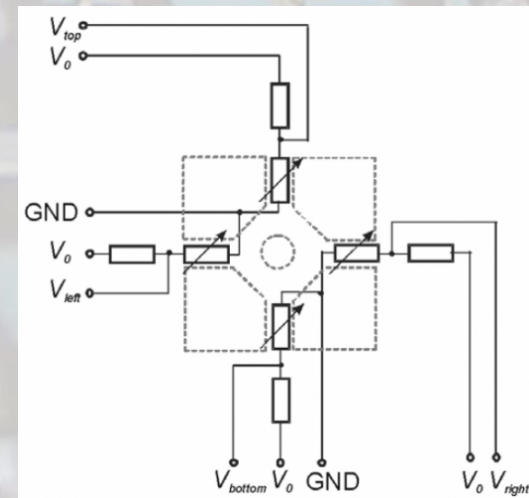
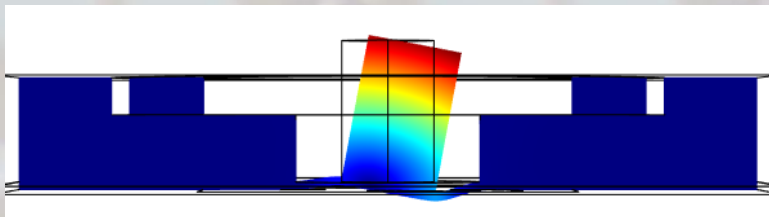
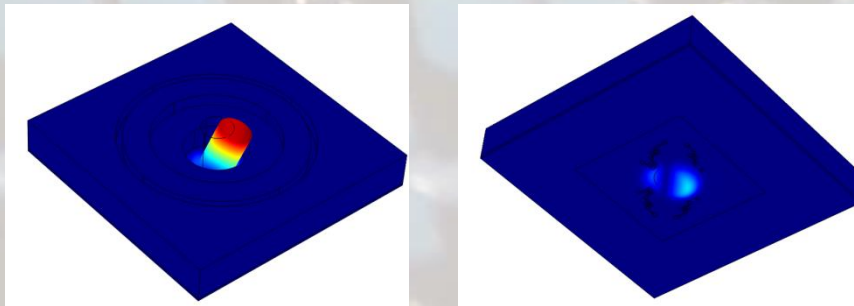
Specific requirements:

- Reduced size (down to $1 \times 1 \text{mm}^2$) to enable integration
- Sensitivity: 1-20N for gripping force, 10-1000mN for tactile sensing
- Robustness (vs. sensitivity)
- Biocompatible coating can withstand sterilization

Operation:

- Deforming c-Si membrane
- 4 embedded piezoresistors
- 4 Voltage dividers or Wheatstone-bridges
- Calculation of vectorial components:

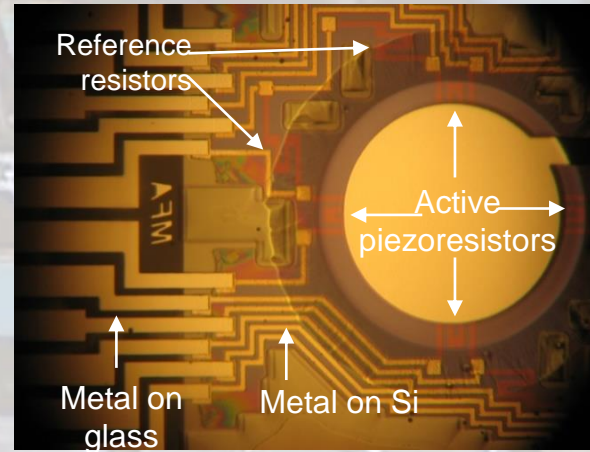
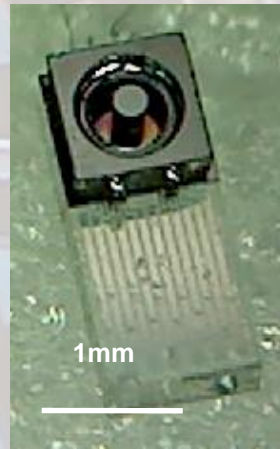
$$F_x = \frac{1}{V_0 \alpha_{ls} \pi_{44}} (\Delta V_{right} - \Delta V_{left}),$$
$$F_y = \frac{1}{V_0 \alpha_{ls} \pi_{44}} (\Delta V_{top} - \Delta V_{bottom}),$$
$$F_z = \frac{1}{V_0 \alpha_{ls} \pi_{44}} \frac{(\Delta V_{left} + \Delta V_{right} + \Delta V_{top} + \Delta V_{bottom})}{2}$$



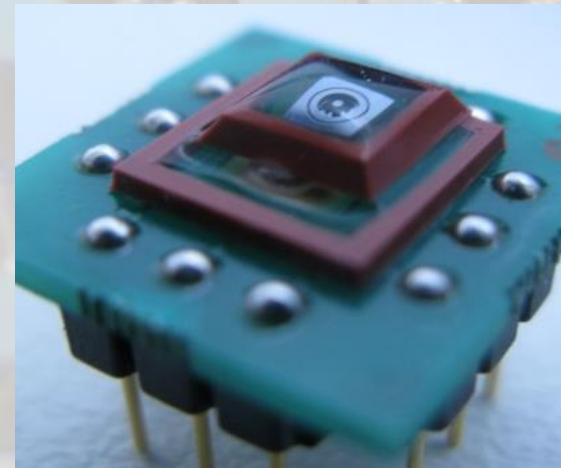
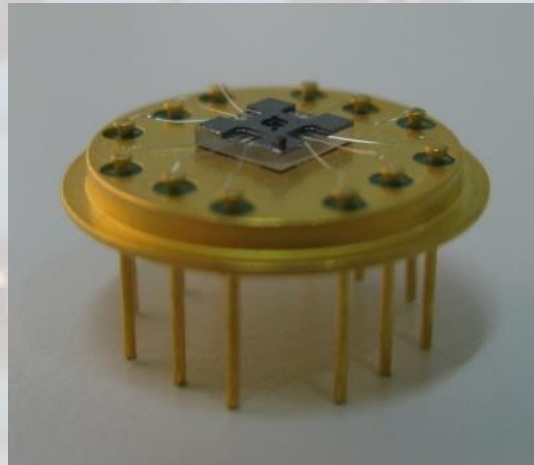
Piezoresistive 3D force sensors - Integration in a laparoscopic tool

Previous work

- Fabrication



- Testing



Piezoresistive 3D force sensors - Integration in a laparoscopic tool

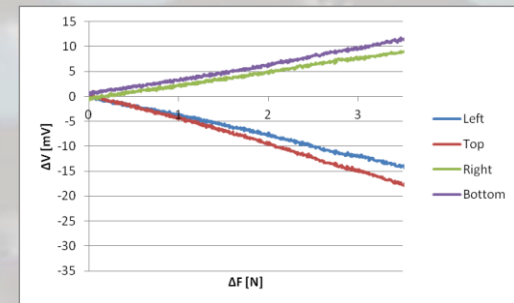
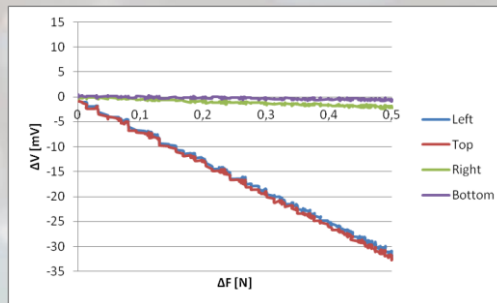
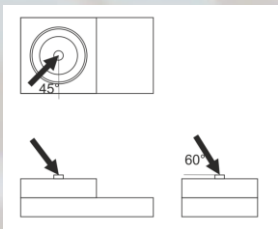
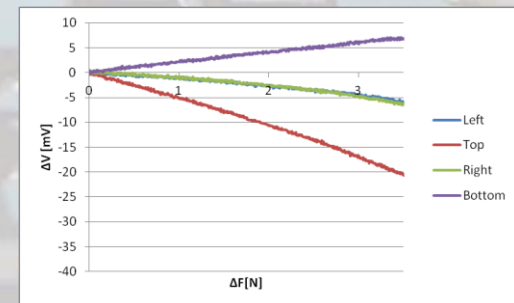
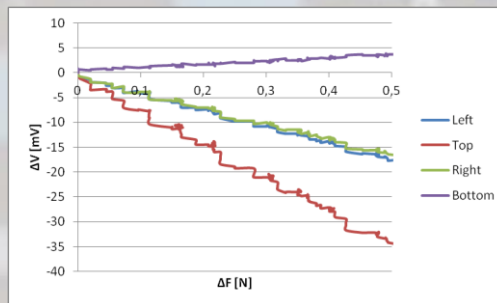
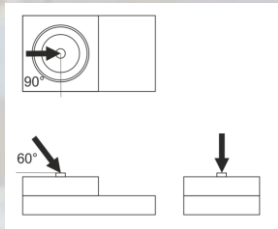
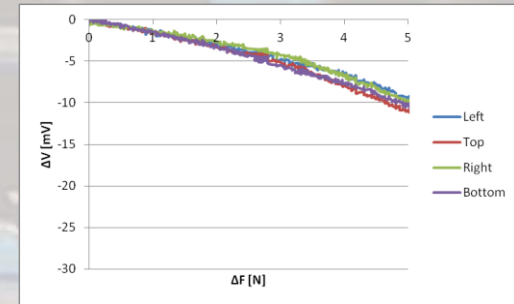
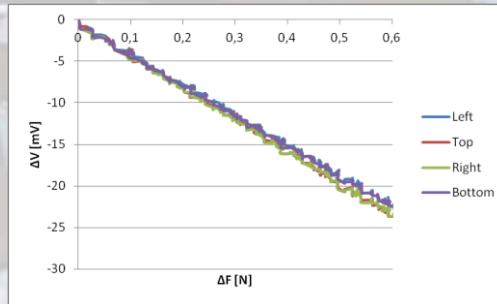
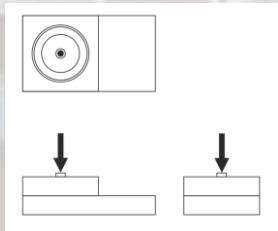
Previous work

- Measurements

Effect of elastic coating

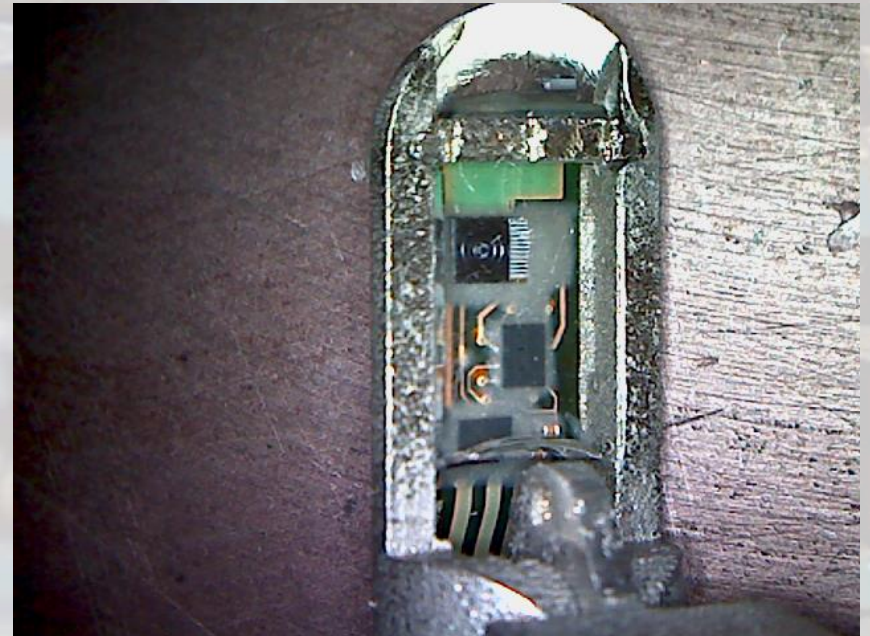
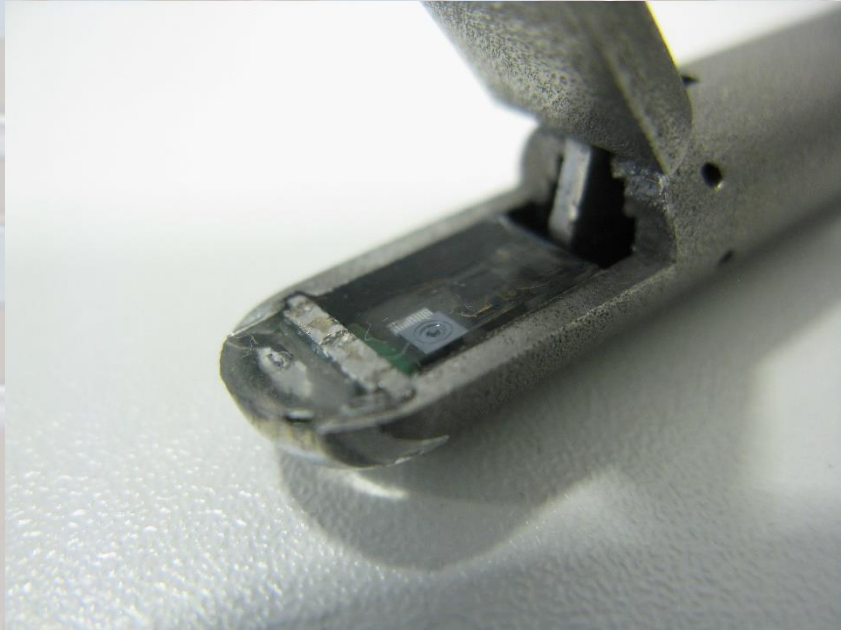
Bare sensor

Covered sensor



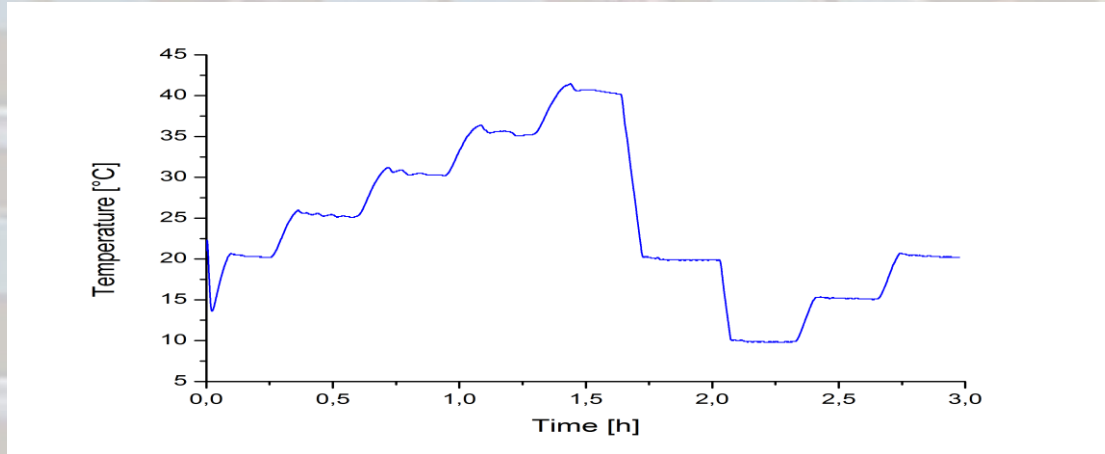
Piezoresistive 3D force sensors - Integration in a laparoscopic tool

Previous work – metal gripper and biocompatible coating (Nusil MED-6215)

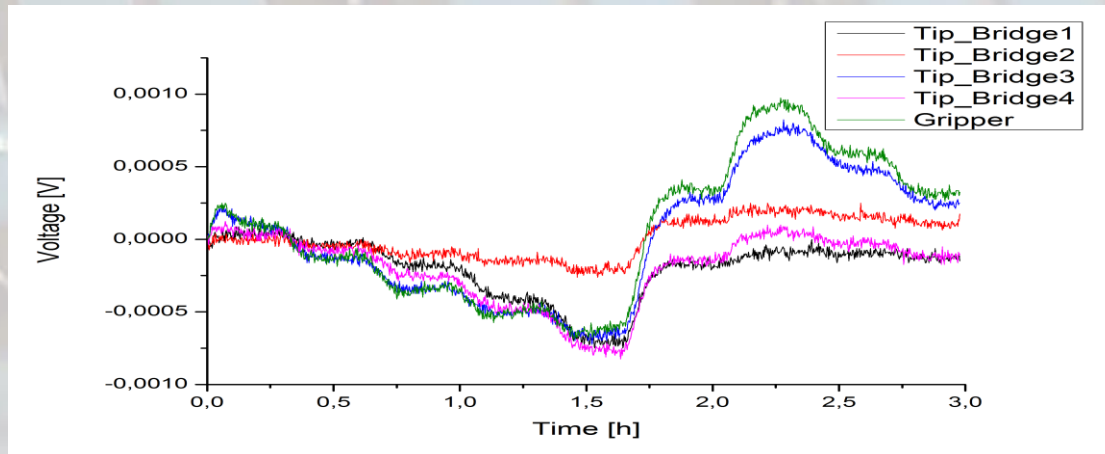


Piezoresistive 3D force sensors - Integration in a laparoscopic tool

Previous work – temperature tests



Temperature profile



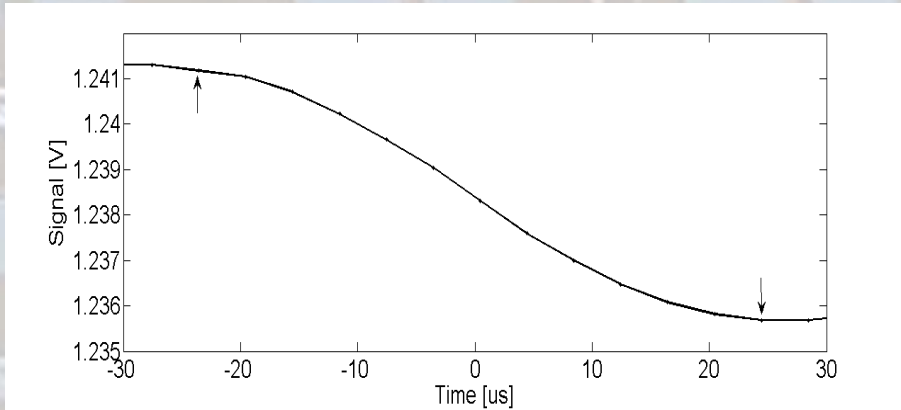
Offset signals



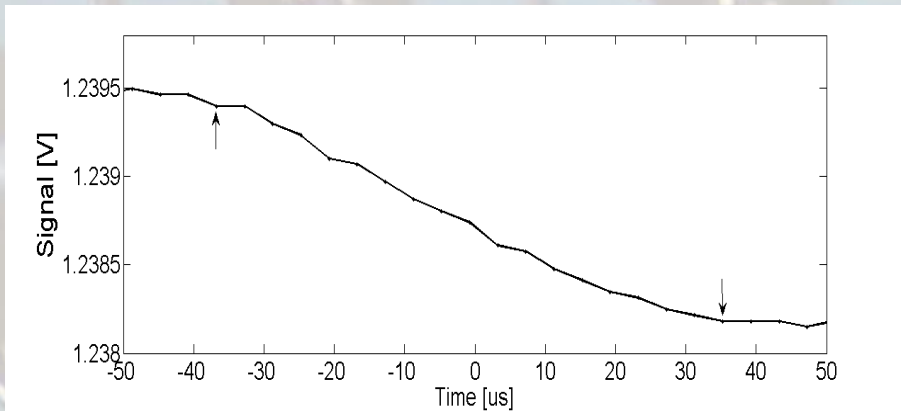
Climate chamber

Piezoresistive 3D force sensors - Integration in a laparoscopic tool

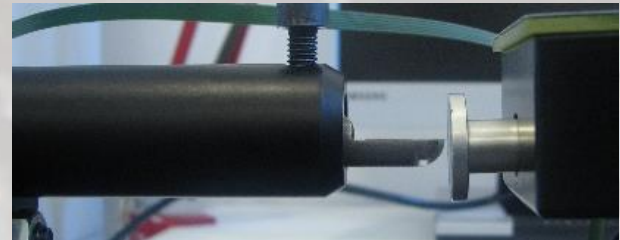
Previous work – response time



Bare sensor

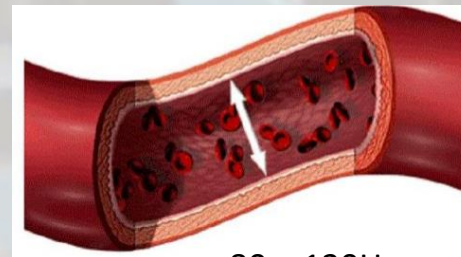
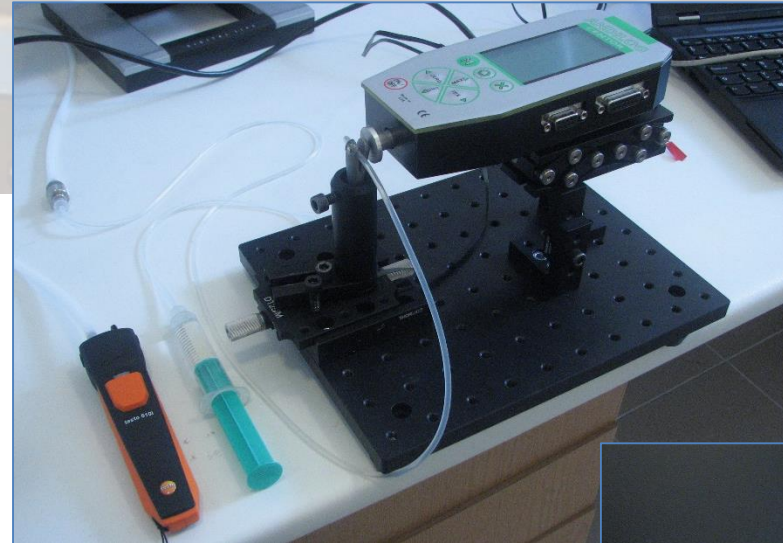
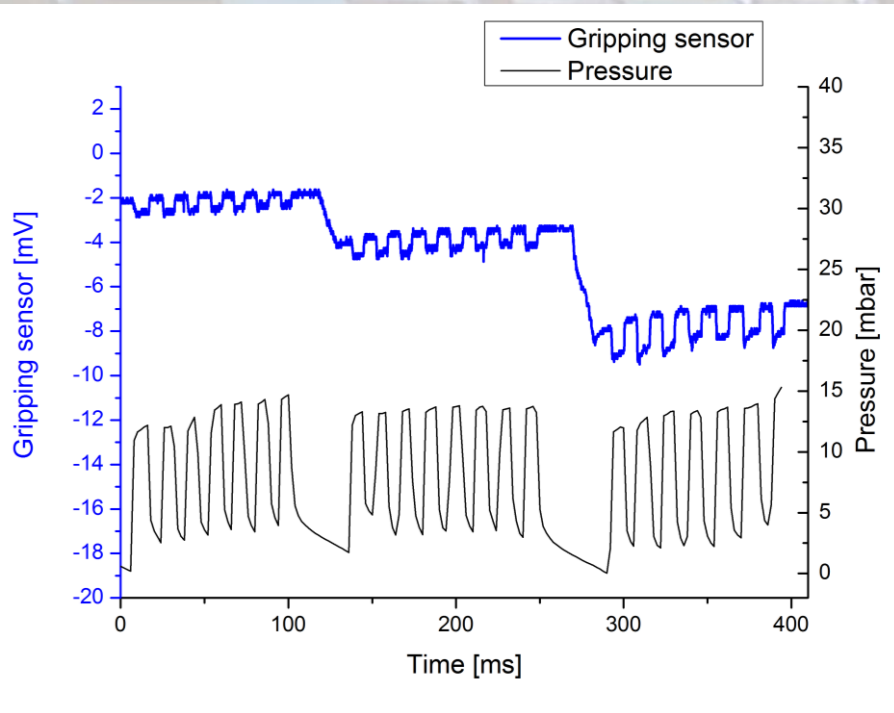


Covered sensor

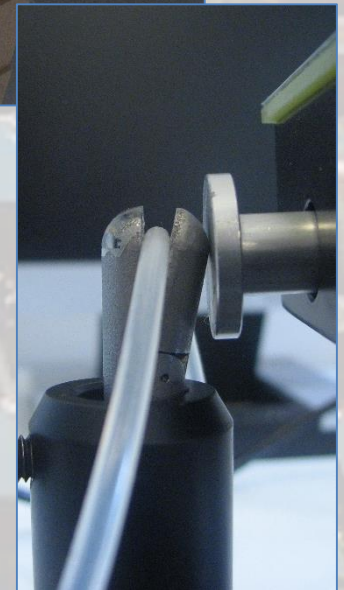


Piezoresistive 3D force sensors - Integration in a laparoscopic tool

Previous work – biomechanical tests

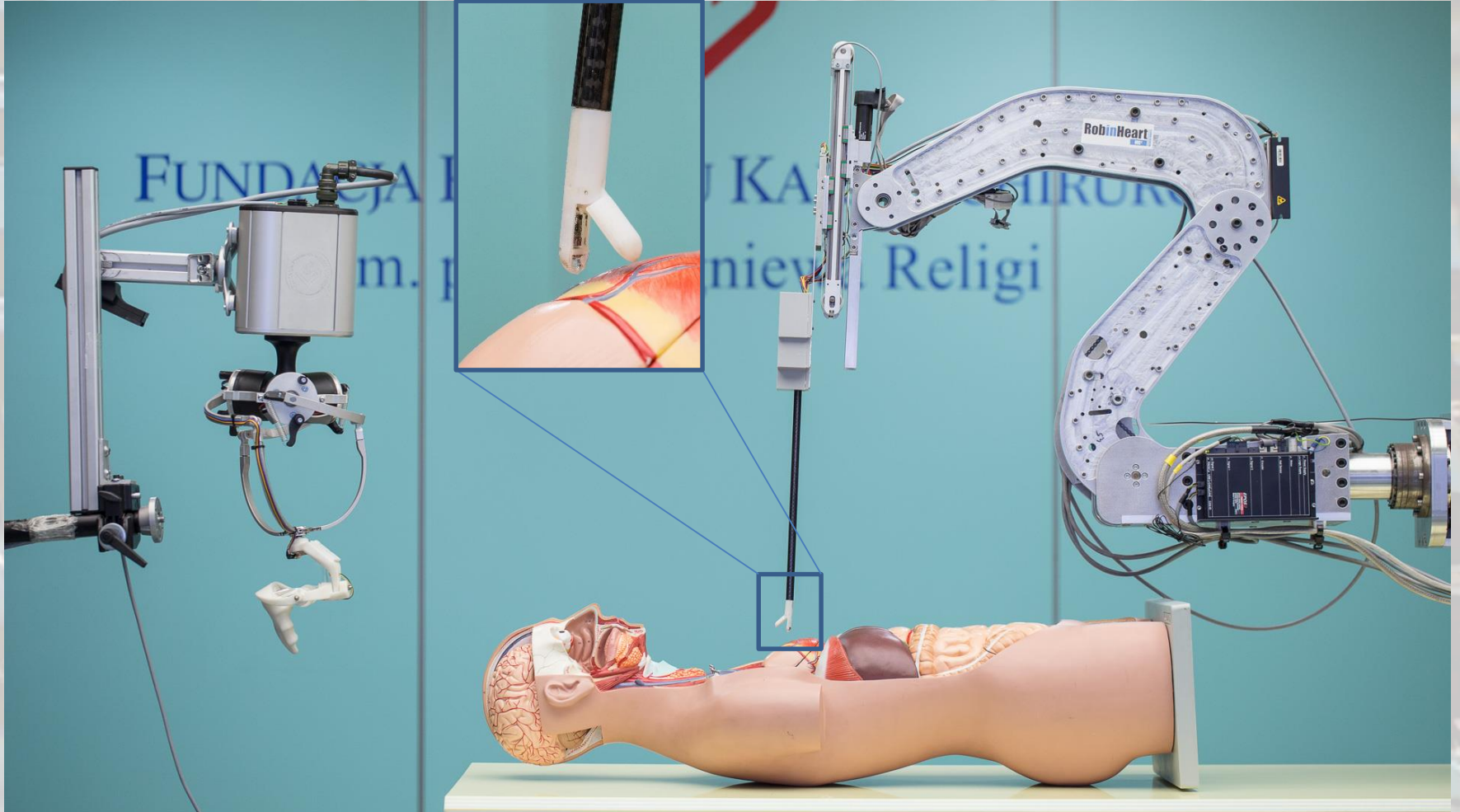


80 – 120Hgmm
106 – 160mBar



Piezoresistive 3D force sensors - Integration in a laparoscopic tool

Previous work – completed test device



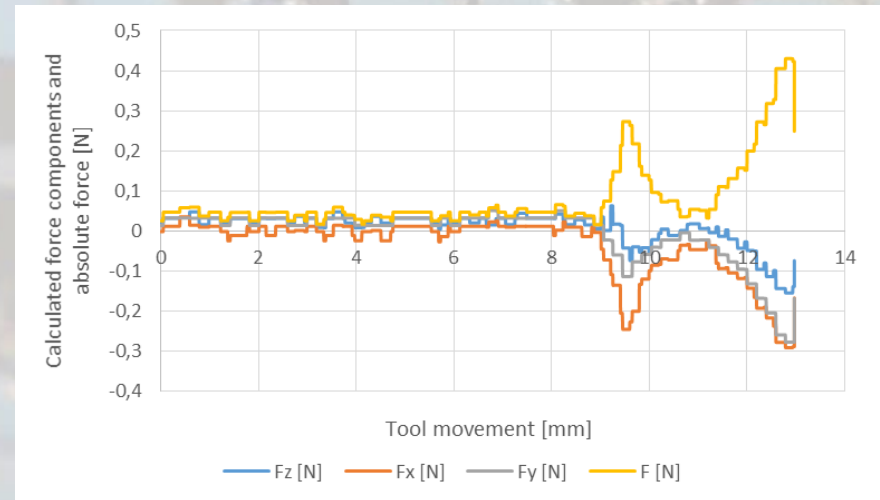
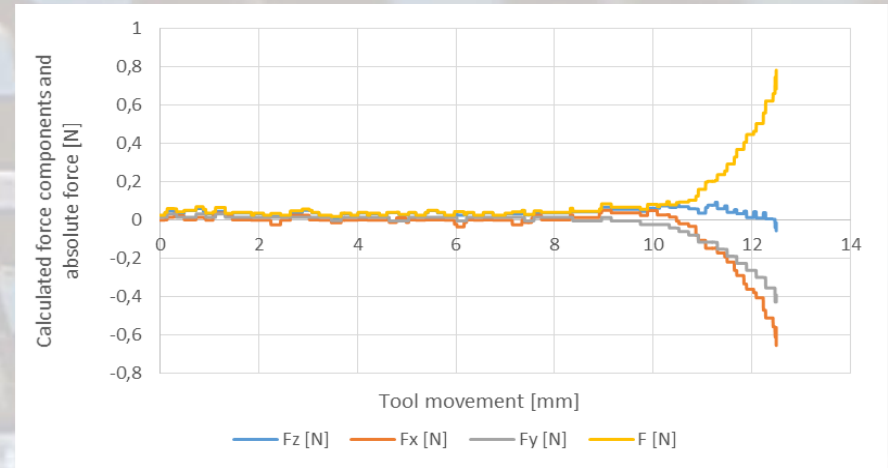
Piezoresistive 3D force sensors - Integration in a laparoscopic tool

Previous work – biomechanical tests



Piezoresistive 3D force sensors - Integration in a laparoscopic tool

Previous work – biomechanical tests

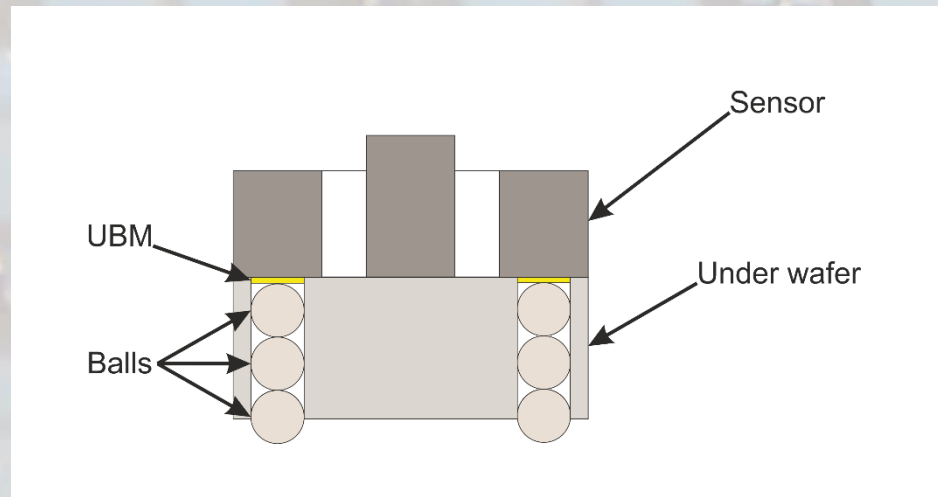
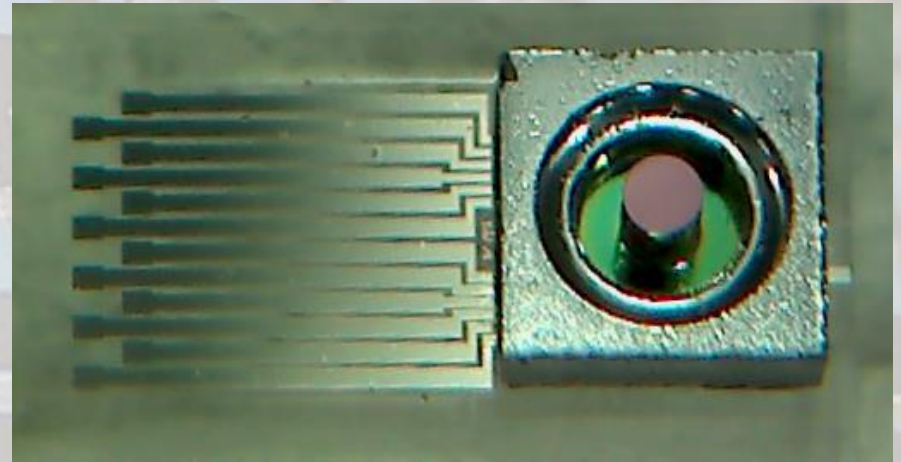


Piezoresistive 3D force sensors – Reducing chip size

(Supported by the ÚNKP-17-3-I-OE-779/47 New National Excellence Program of the Ministry Of Human Capacities)

Means:

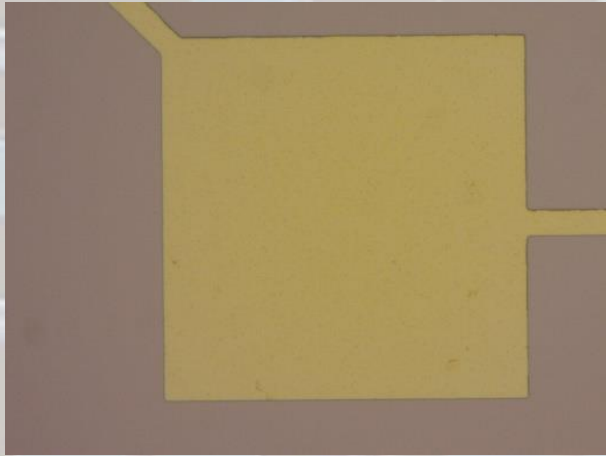
- Replacement of glass substrate
- Application of new contacts
- Design new read-out electronics



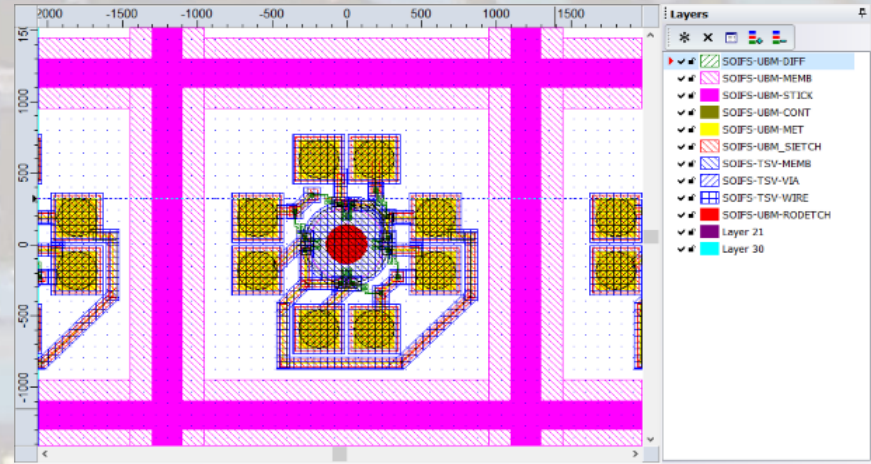
Piezoresistive 3D force sensors - Reducing chip size

(Supported by the ÚNKP-17-3-I-OE-779/47 New National Excellence Program of the Ministry Of Human Capacities)

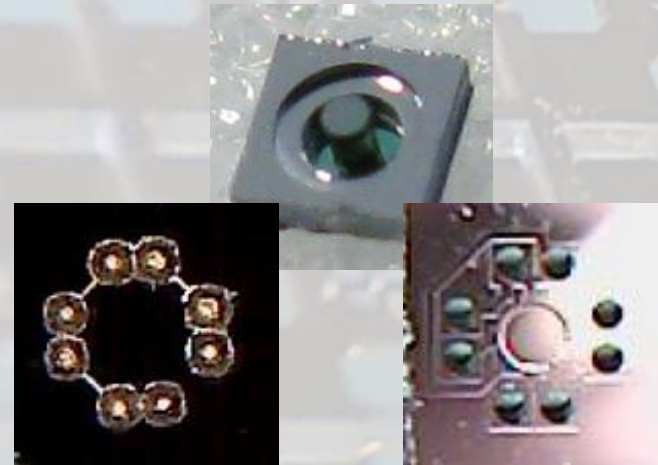
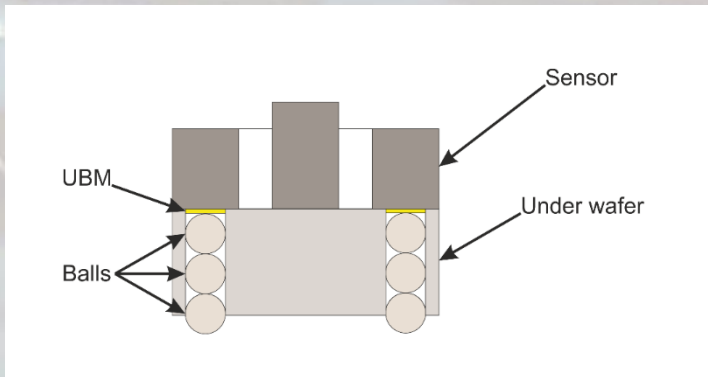
Under bump metallization



Design and layouts



Top and bottom parts



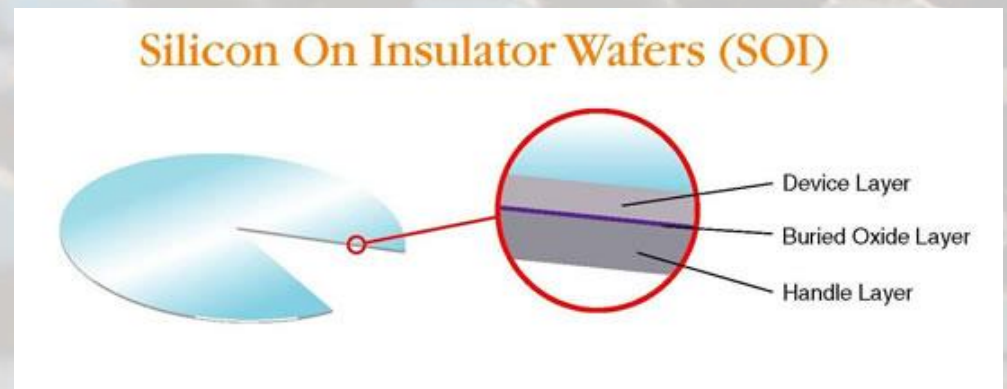
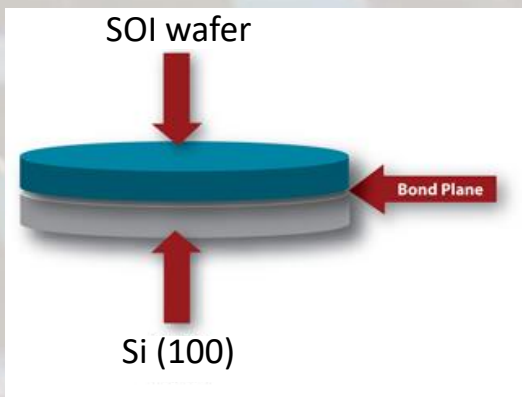
Piezoresistive 3D force sensors - Reducing chip size

(Supported by the ÚNKP-17-3-I-OE-779/47 New National Excellence Program of the Ministry Of Human Capacities)

Wafer bonding

Aspects:

- Importance of cleanness of the surface
- Strong bond at low temperature
- Hard structured geometry
- Oxidized surface or native oxide?



Piezoresistive 3D force sensors - Integration in a laparoscopic tool

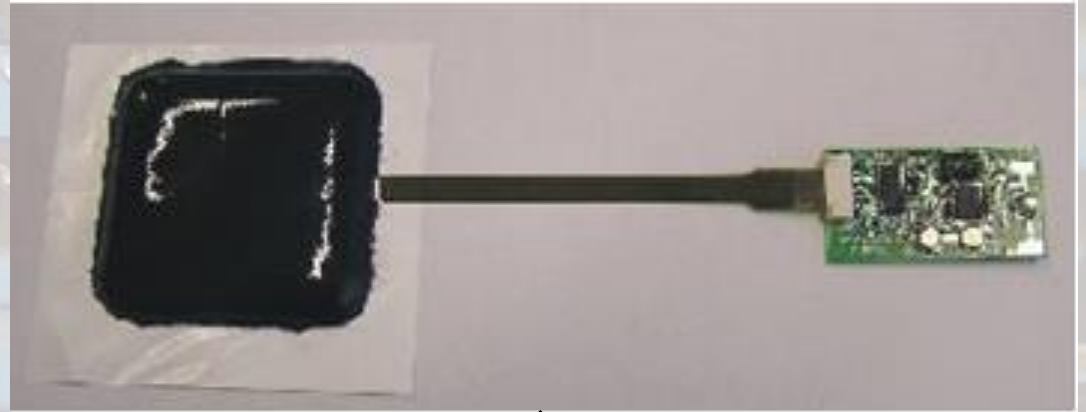
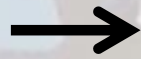
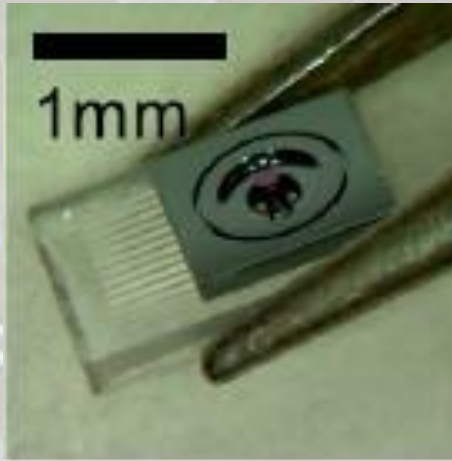
Publications in this topic

- **5 Papers (min. 4. pages)**
- **5 oral presentations (in English)**
- **3 posters**

Piezoresistive 3D force sensors - Integration in a vehicle tyre

Previous work

- Implantation of 3D force sensor in a special rubber



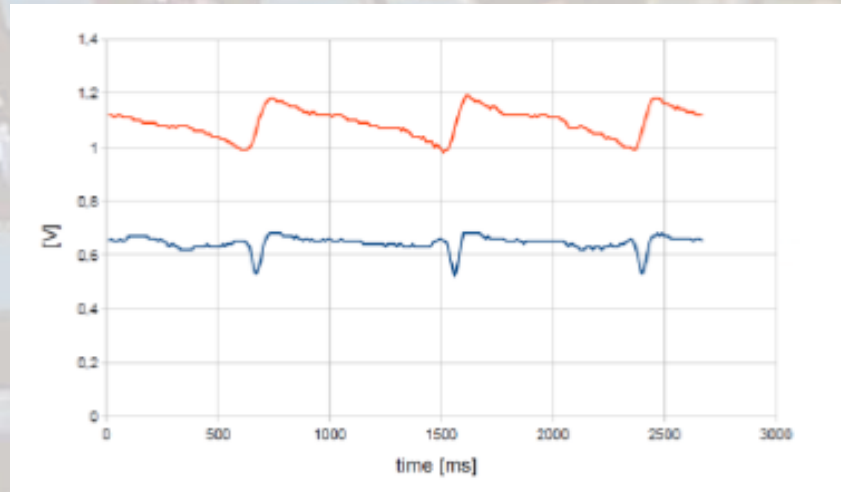
- Integration of test tool in a vehicle tyre



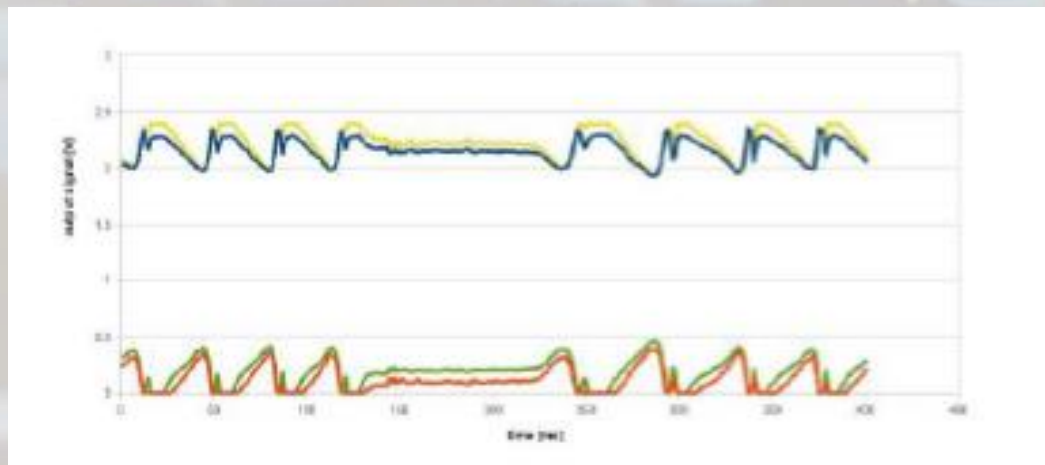
Piezoresistive 3D force sensors - Integration in a vehicle tyre

Previous work

- Measurements – normal road conditions



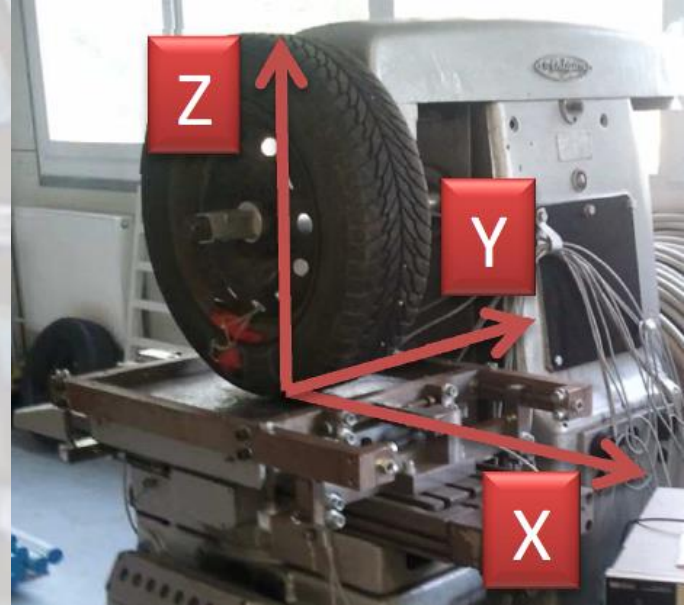
- Measurements – the wheel is blocked



Piezoresistive 3D force sensors - Integration in a vehicle tyre

Previous work

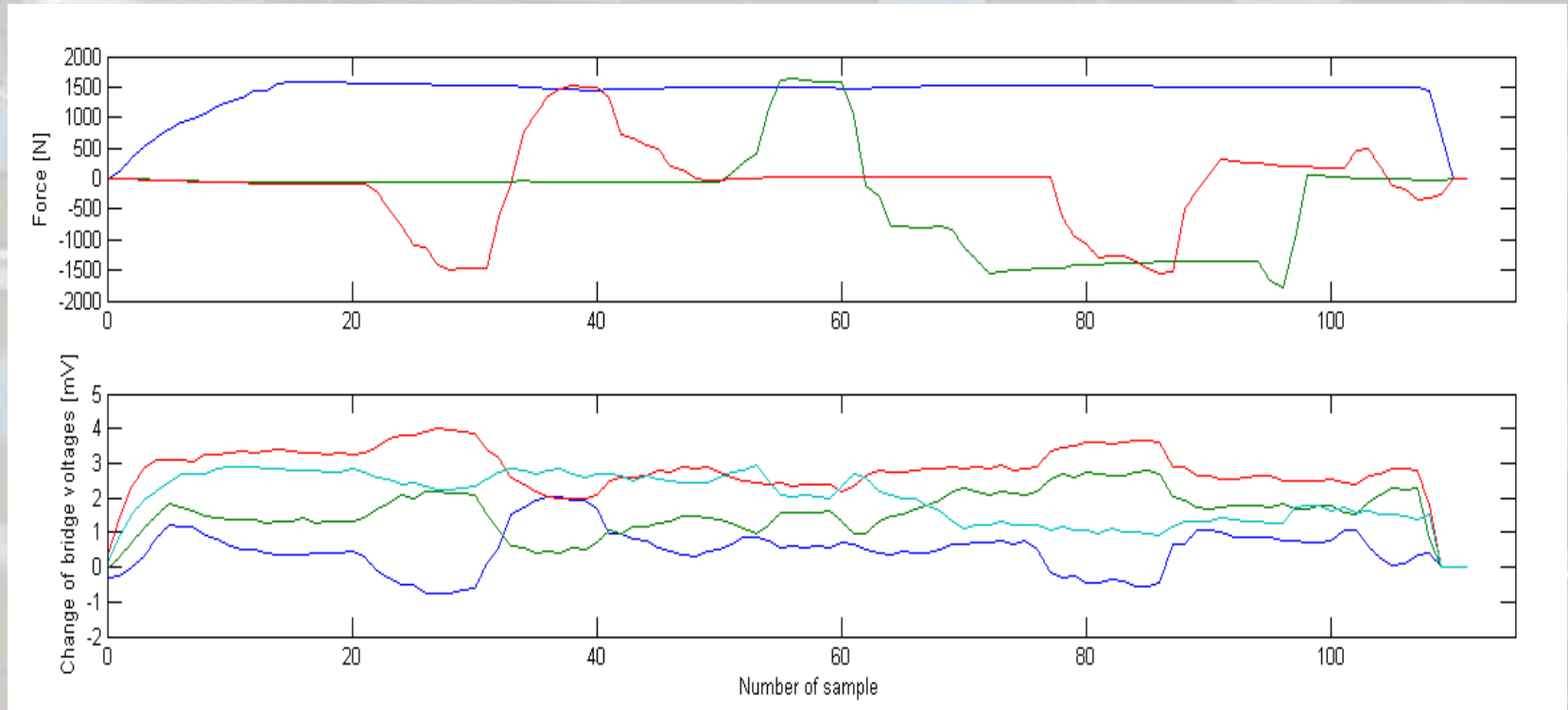
- Functional test: static loading



Piezoresistive 3D force sensors - Integration in a vehicle tyre

Previous work

- Results of static measurement

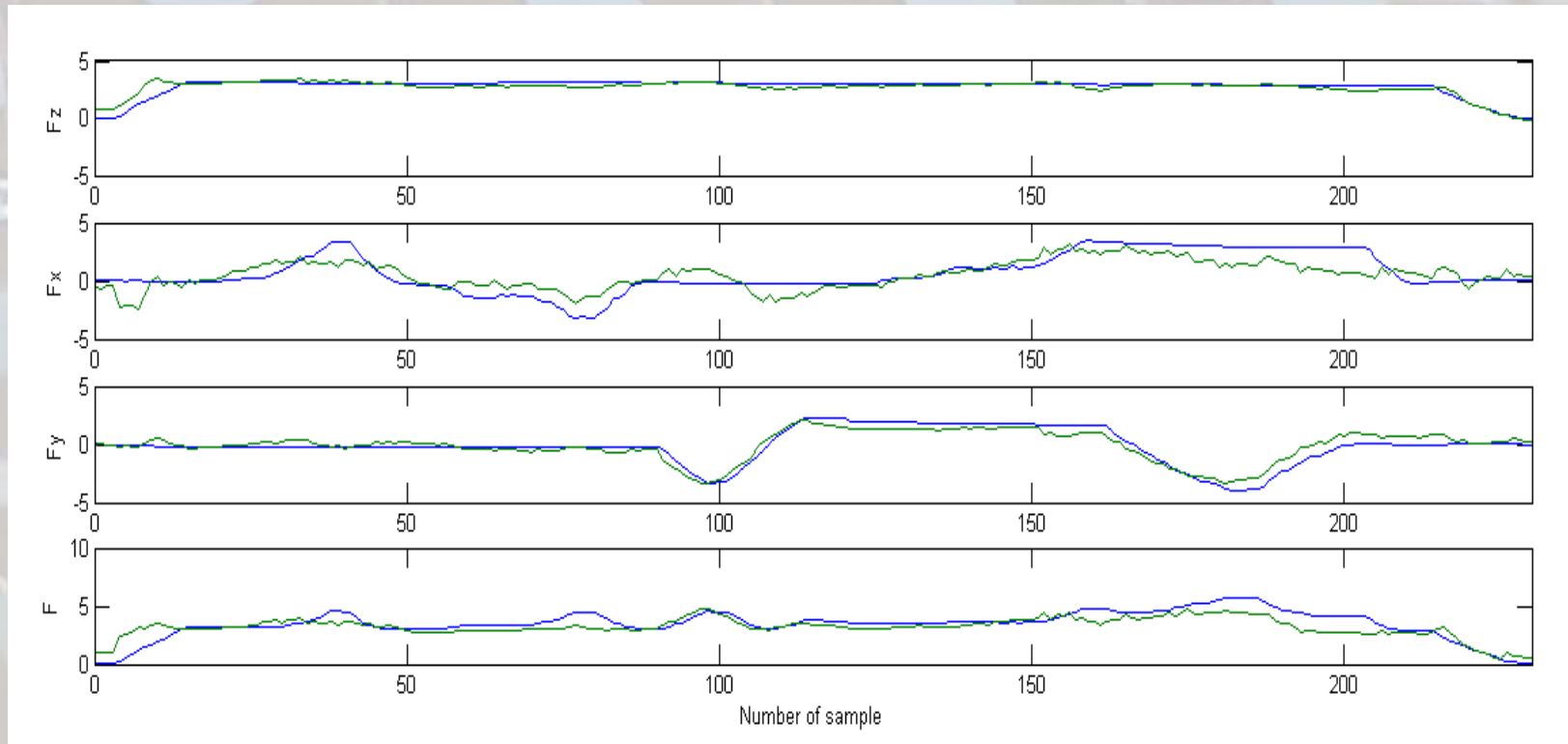


F_x ———
 F_y ———
 F_z ———

Piezoresistive 3D force sensors - Integration in a vehicle tyre

Previous work

- **Multiple regression:** demonstration of proportional relationship between tyre deformation and acting forces on the wheel



Piezoresistive 3D force sensors - Integration in a vehicle tyre

Current work

- New wireless read-out electronic
- Definition of the sensor position based on the results of the static measurement



Piezoresistive 3D force sensors - Integration in a vehicle tyre

Future work

- Preliminary tests at the KFKI Campus
- Further tests in Győr

Publications in this topic

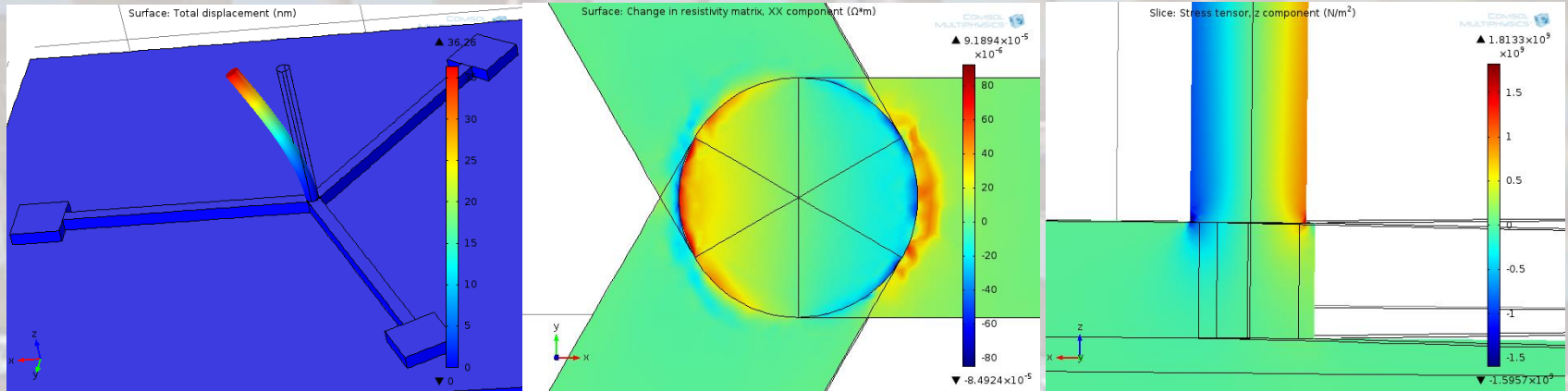
Oral presentation (in English):

- J. Radó, G. Battistig, S. Kuliniy, R. Végvári, I. Bársony, **Monitoring the tyre deformation on a vehicle on the run**, EUROSENSORS 2016, Budapest, Hungary

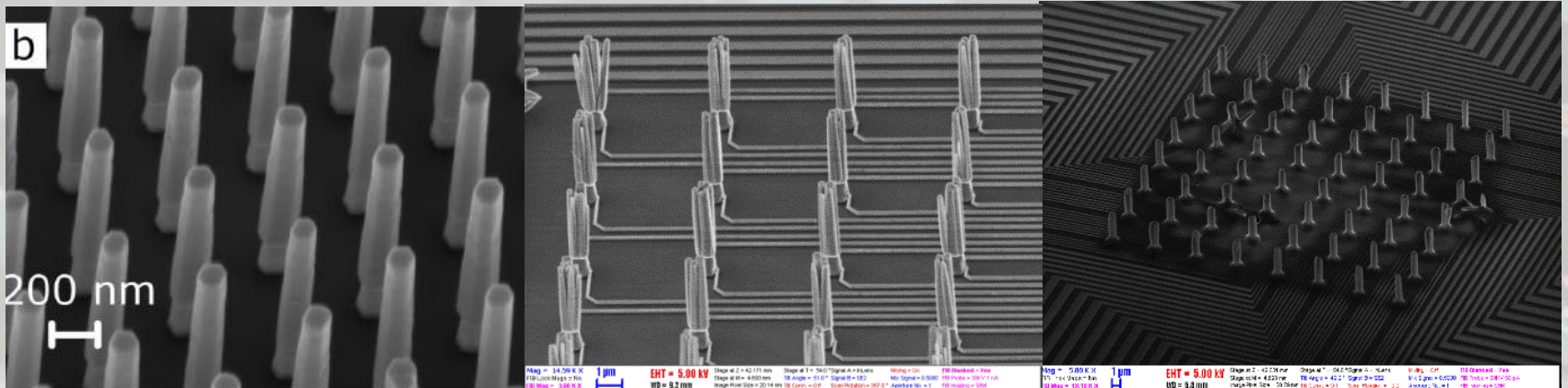
Piezoelectric ZnO nano-rods – for high-resolution fingerprint sensing

Previous work

- Simulation



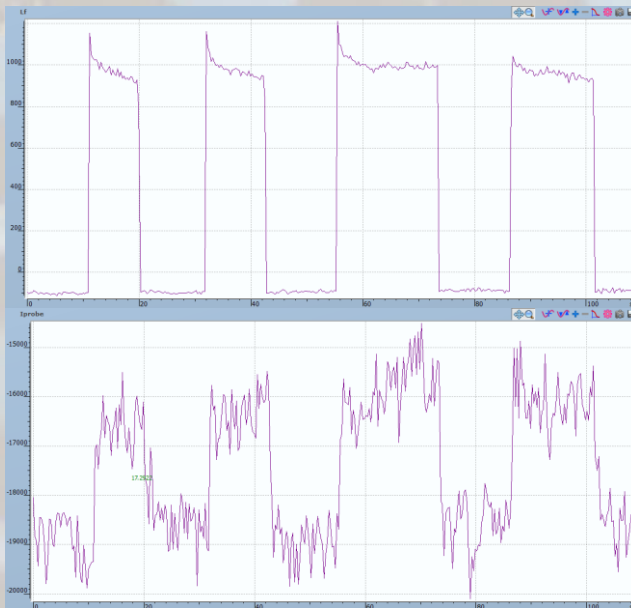
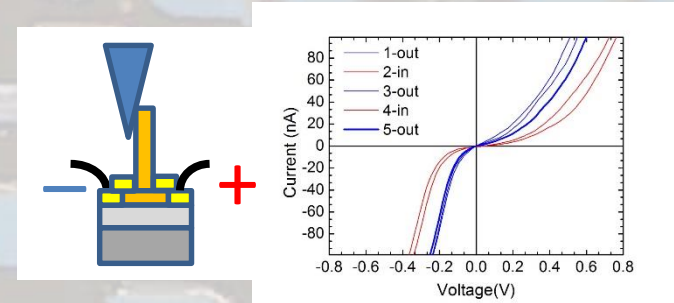
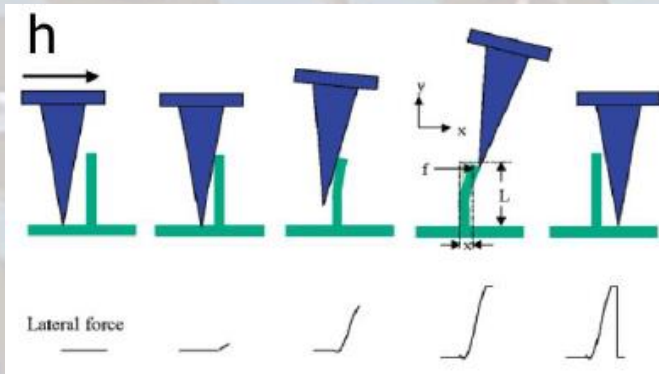
- Growing of the rods (hydrothermal growing: Zinc-nitrate hexahydrate and hexamethylen tetramin)



Piezoelectric ZnO nano-rods – for high-resolution fingerprint sensing

Previous work

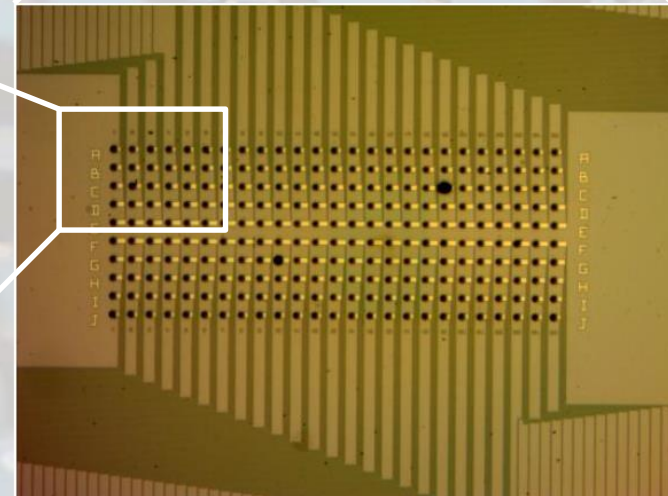
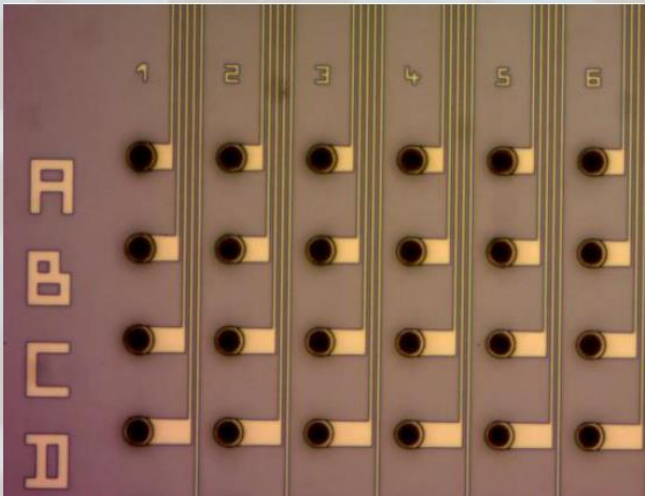
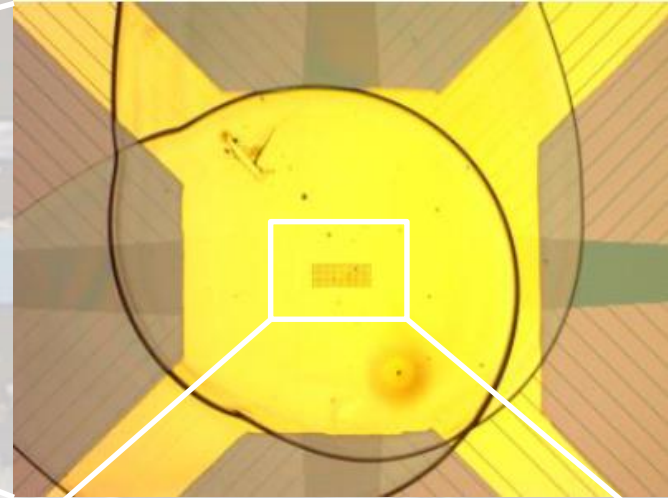
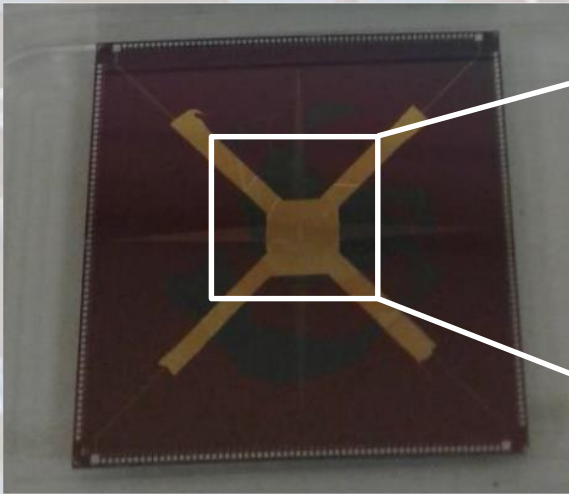
- Bending and measurement in Atomic Force Microscope



Piezoelectric ZnO nano-rods – for high-resolution fingerprint sensing

Previous work

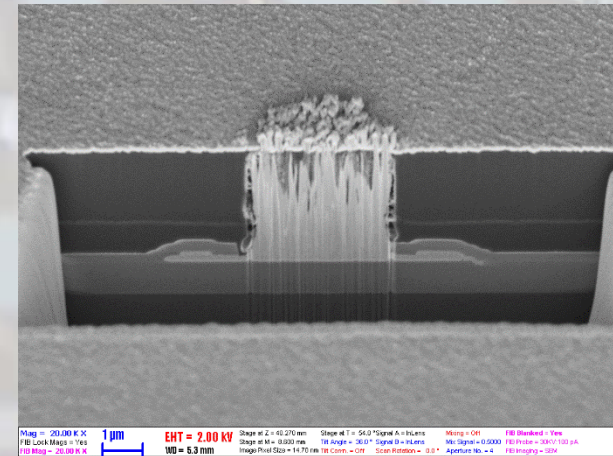
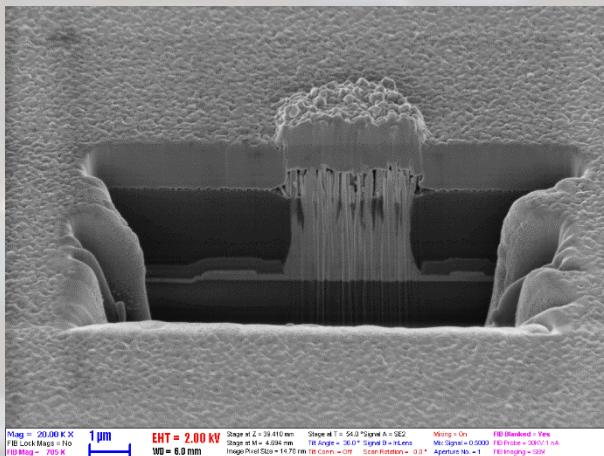
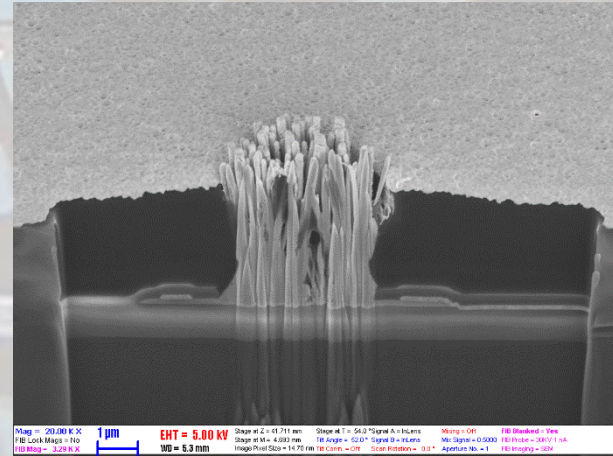
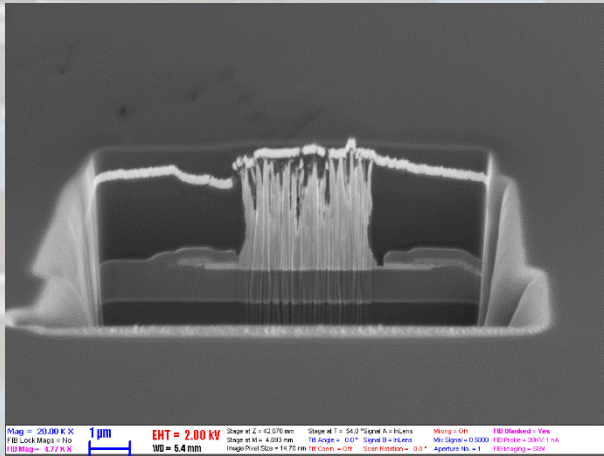
- Design and fabrication a 25x10 nano-array



Piezoelectric ZnO nano-rods – for high-resolution fingerprint sensing

Previous work

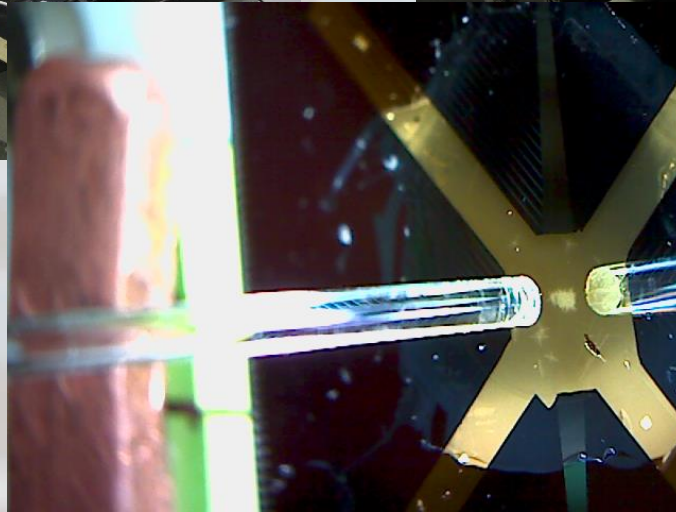
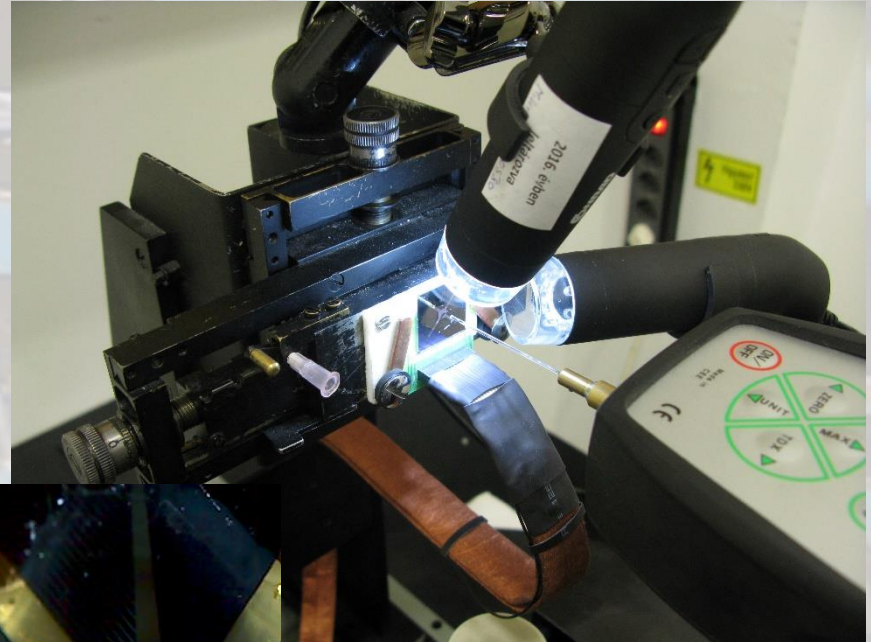
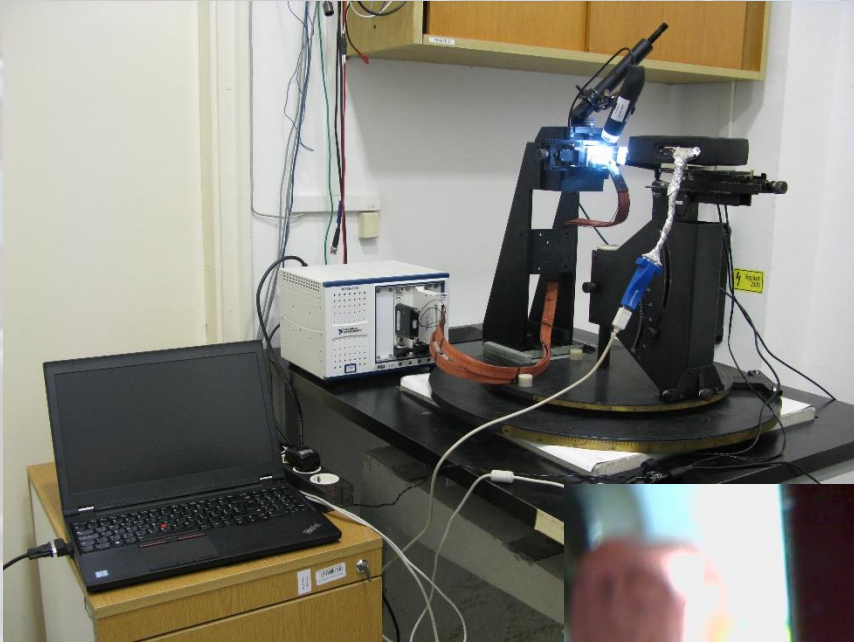
- Design and fabrication a 25x10 nano-array



Piezoelectric ZnO nano-rods – for high-resolution fingerprint sensing

Previous work

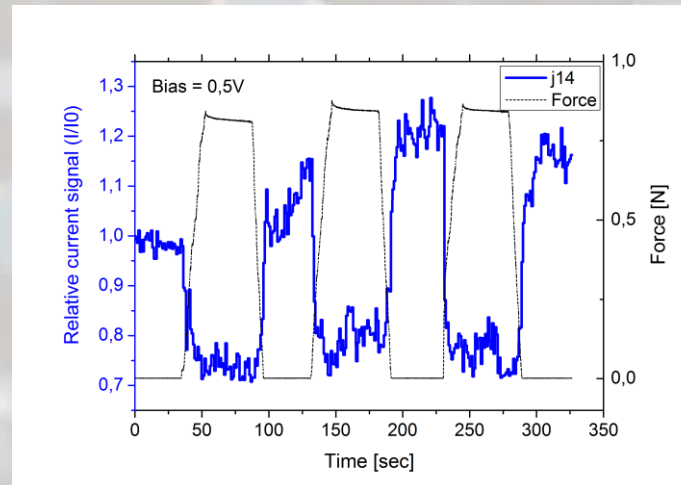
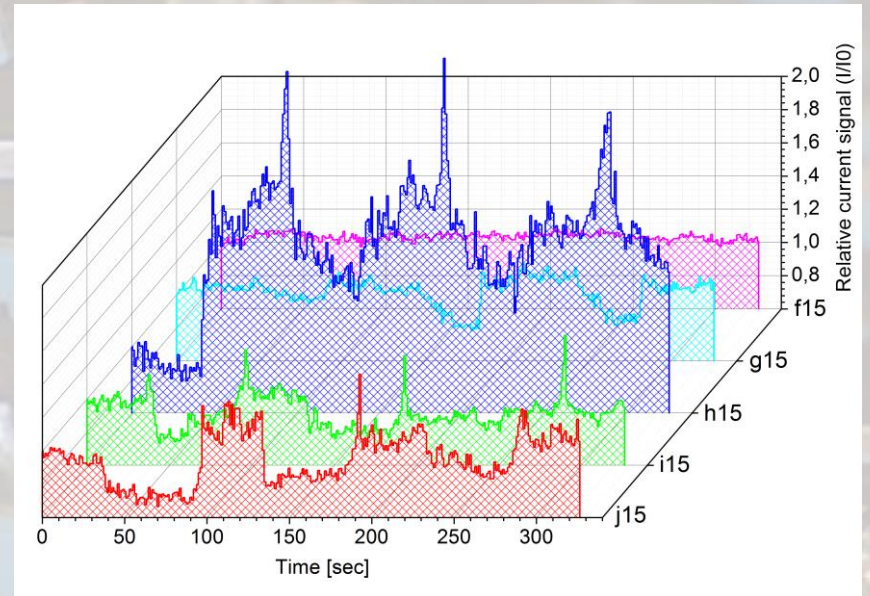
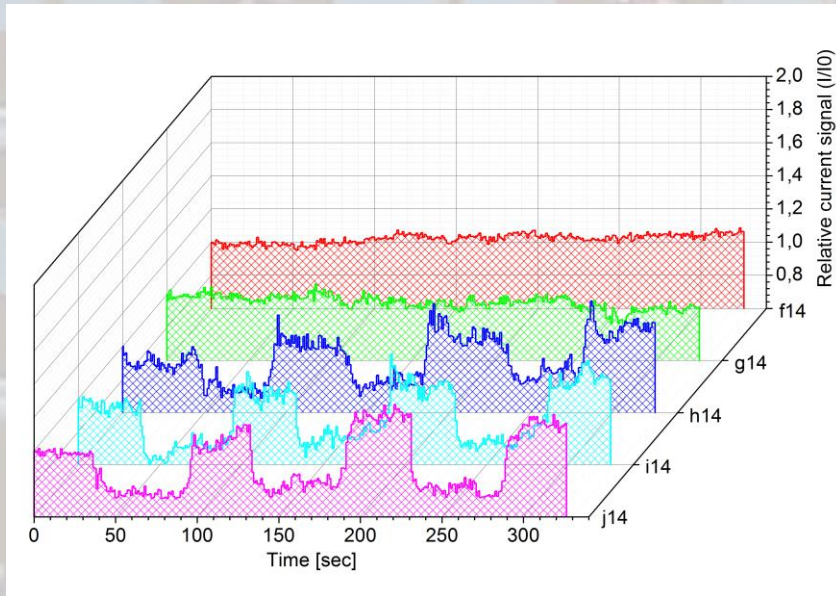
- Assembling a new measurement setup



Piezoelectric ZnO nano-rods – for high-resolution fingerprint sensing

Previous work

- Results



Piezoelectric ZnO nano-rods – for high-resolution fingerprint sensing

The screenshot displays the PXIe.vi software interface, which is used for controlling and monitoring a measurement system. The interface is divided into several sections:

- Top Menu:** File, Edit, View, Project, Operate, Tools, Window, Help.
- Control Panel:** Includes buttons for 'Cont.', 'IV', and 'Map'. Below this is a large grid representing a force map, with colors ranging from blue (low force) to red (high force). A vertical color scale on the right indicates force values from -2.000000E-1 to 8.000000E-1.
- Force Measurement:** A digital display shows the current force as **0,589**. Below it is a graph showing the force over time, with the y-axis labeled 'Force [N]' ranging from -2.000000E-1 to 8.000000E-1.
- Video Feed:** A live video stream shows a probe tip (with a red ring) in contact with a sample. The video is saved in the directory `C:\Users\Radó János\Documents\Scope\pictures`.
- Configuration and Control:** Fields for 'Identifier 1' (containing 'p01_33') and 'Identifier 2'. A 'Points' button and a yellow 'Calibrate' button with a green checkmark are also present. A 'Message' area is at the bottom right, and a red 'STOP' button is located below it.

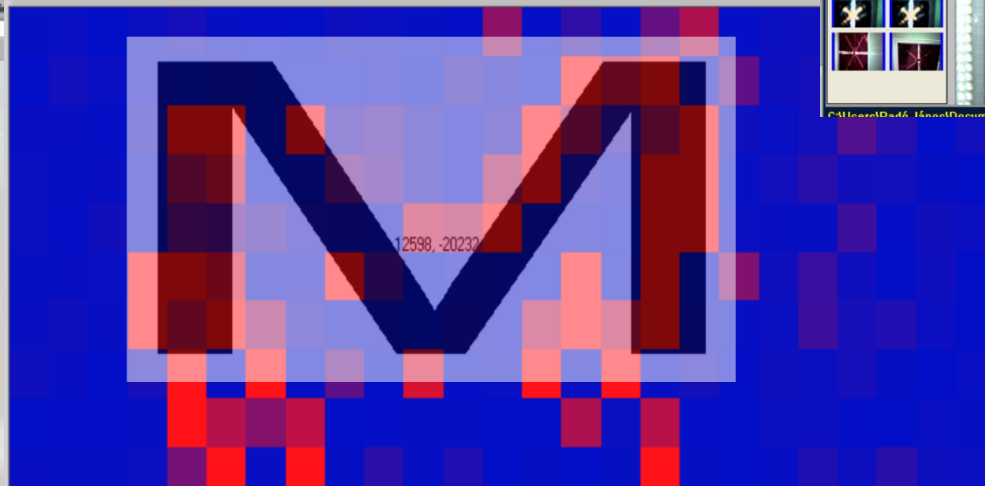
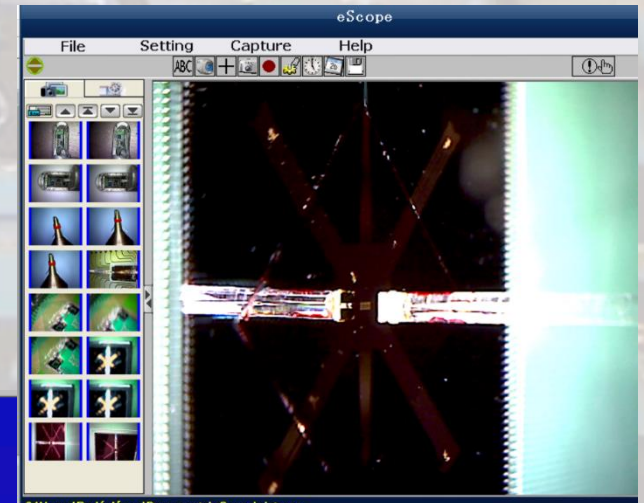
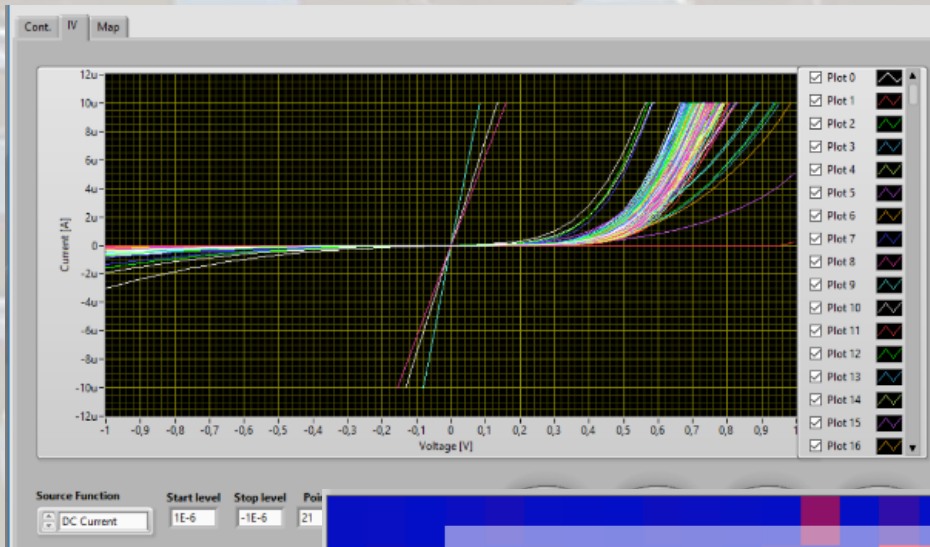
The Windows taskbar at the bottom shows the system tray with the time 17:56 and date 2017.06.06. The active window title is 'NI-PXIe.lvproj/My Computer'.

Piezoelectric ZnO nano-rods

(Supported by the ÚNKP-17-3-I-OE-779/47 New National Excellence Program of the Ministry Of Human Capacities)

Current work

- Pushing the whole array (250 nano-rods) with an M-letter



Piezoelectric ZnO nano-rods

Publications in this topic

Papers

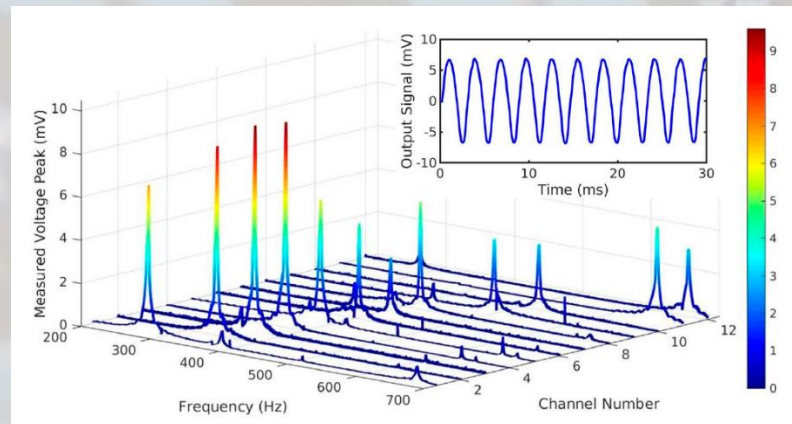
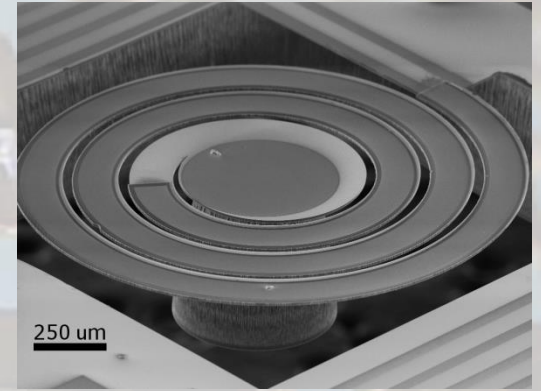
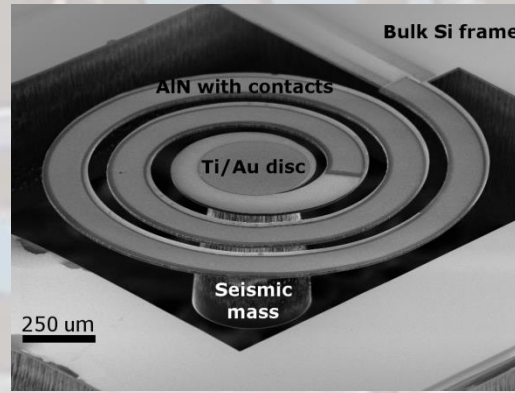
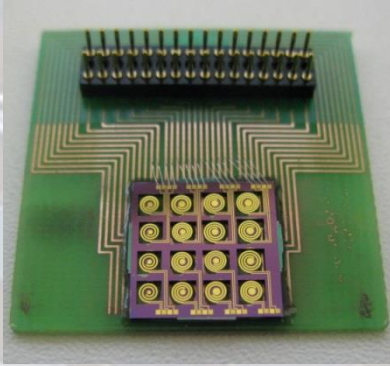
- Bouvet-Marchand A, Graillet A, Volk J, Dauksevicius R, Sturm C, Grundmann M, Saoutieff E, Viana A, Christian B, Lebedev V, Rado J, Lukacs I E, N Q Khanh, Grosso D, Loubat C, **Design of UV-crosslinked polymeric thin layers for encapsulation of piezoelectric ZnO nanowires for pressure-based fingerprint sensors**, JOURNAL OF MATERIALS CHEMISTRY C in press: p. in press. (2018)
- Seifikar Masoud, Christian Björn P, Volk János, Radó János, Lukács István E, Dauksevicius Rolanas, Gaidys Rimvydas, Lebedev Vadim, Viana Antoine, O'Reilly Eoin P, **Direct observation of spontaneous polarization induced electron charge transfer in stressed ZnO nanorods**, NANO ENERGY 43: pp. 376-382. (2018)

Oral presentation:

- János Volk, István E. Lukács, Nguyen Quoc Khánh, János Radó, Róbert Erdélyi: **Bottom contacted piezoelectric nanowire arrays**, NGPT 2016, Rome, Italy
- J. Volk, J. Radó, I. E. Lukács, N. Q. Khánh, R. Erdélyi, G. Battistig, C. Sturm, M. Grundmann, A. Graillet, C. Loubat: **Integrated piezoelectric nanowire arrays for high resolution tactile mapping**, EUROSENSORS 2016, Budapest, Hungary

Piezoelectric AlN thin film for 3D force sensor

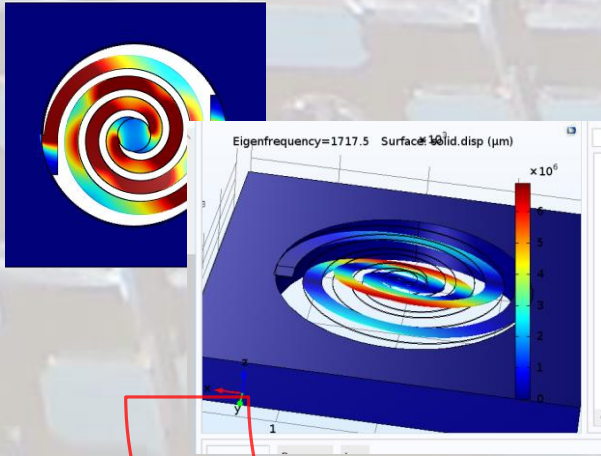
Previous work



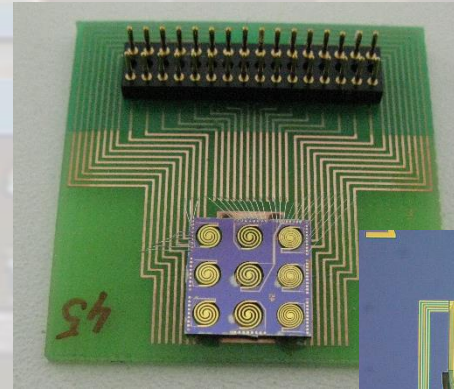
Piezoelectric AlN thin film for 3D force sensor

Current work

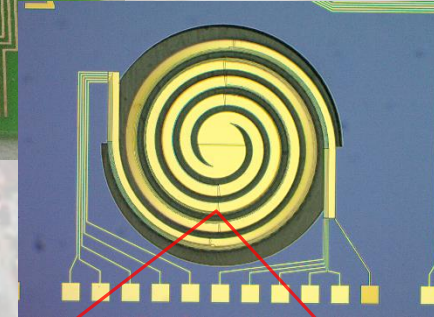
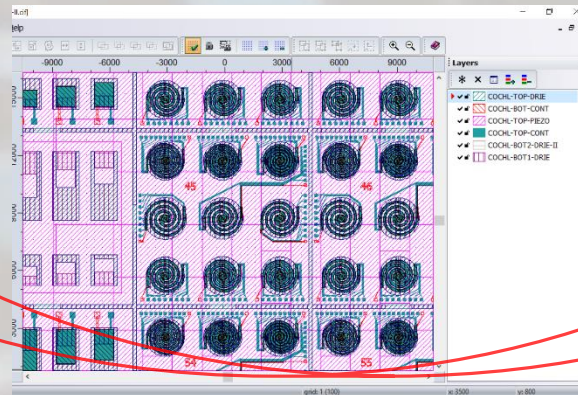
Simulation



Fabrication



Design



Piezoelectric AlN thin film for 3D force sensor

Publications in this topic

Paper

Udvardi Péter, Radó János, Straszner András, Ferencz János, Hajnal Zoltán, Soleimani Saeedeh, Schneider Michael, Schmid Ulrich, Révész Péter, Volk János, **Spiral-Shaped Piezoelectric MEMS Cantilever Array for Fully Implantable Hearing Systems**, MICROMACHINES 8:(10) Paper 311. 13 p. (2017)

János Radó, Péter Udvardi, Saeedeh Soleimani, István Bársony, Péter Révész and János Volk, **Low-frequency piezoelectric accelerometer array for fully implantable cochlear implants**, Accepted at Eurosensors 2018

Further information

Completed courses

- Szilárdtest kémia
- Nanotechnológia
- Polimerek kémiája és fizikája
- Mikroelektronikai anyagok és szerkezetek vizsgálati módszerei
- Félvezető technológiák
- Ragasztás mentes szeletkötés
- Mikro és nano elektromechanikus szerkezetek
- Önszerveződő alacsonydimenziós rendszerek

Participation in projects:

- Incite Eniac (Call 2013-1/621278-2)
- PiezoMat (grant no. 611019)
- KoFah (NVKP_16-1-2016-0018)

Further presentations

- Tapintásérzékelés az orvosi robotikában
(MTA Székház-Magyar Tudomány Ünnepe–Emberközpontú Technológia)
- MEMS technológiával előállított 3D erőmérő szenzorok
(Kandó Konferencia 2017)



***Thank you for your
attention!***